

TSV Market Drivers, Demand & Product Readiness

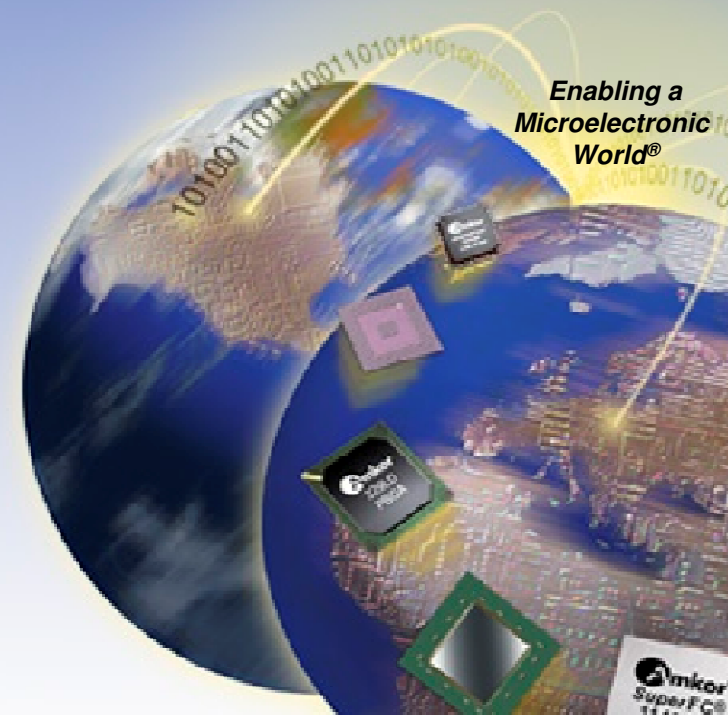
RELIABILITY
& TRUST

信義

R. Huemoeller

SVP, Adv. 3D Interconnect Platform Develop

March 6, 2012





Topics

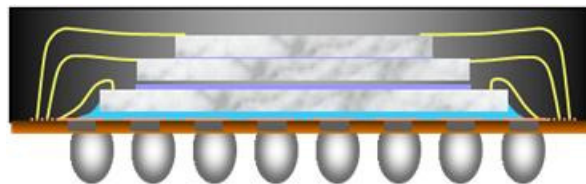
- **TSV Platform Drivers**
- **Interposer Supply Chain Logistics**
- **Product Offerings & Timing**
- **Conclusion**



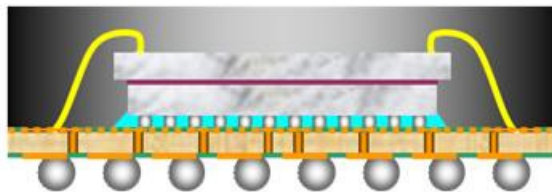
TSV Platform Drivers

“Technology Convergence”

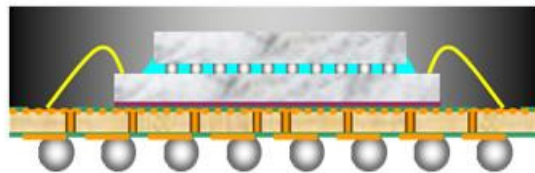
Stacked CSP (SCSP) – Migration to TSV



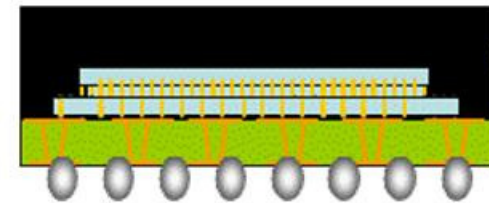
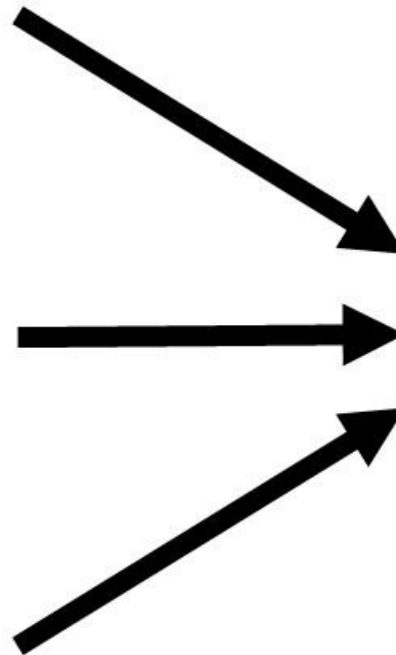
Stacked CSP



FlipStack® CSP



F2F FlipStack®



TSV Stacked CSP

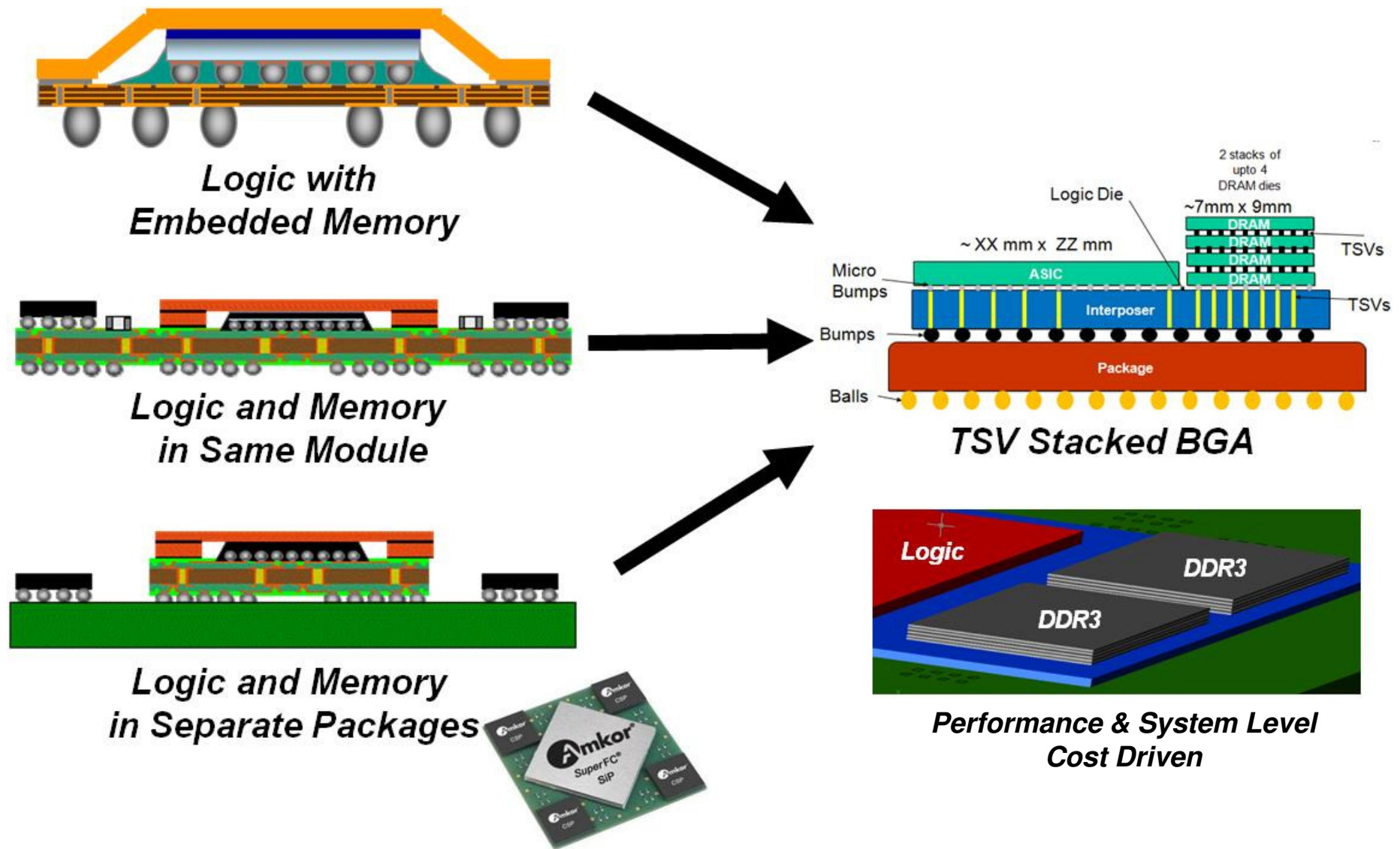
Performance Driven

Compared to POP Memory

- 8x performance in bandwidth
- 50% power savings

Courtesy of Samsung

FCBGA – Migration to TSV

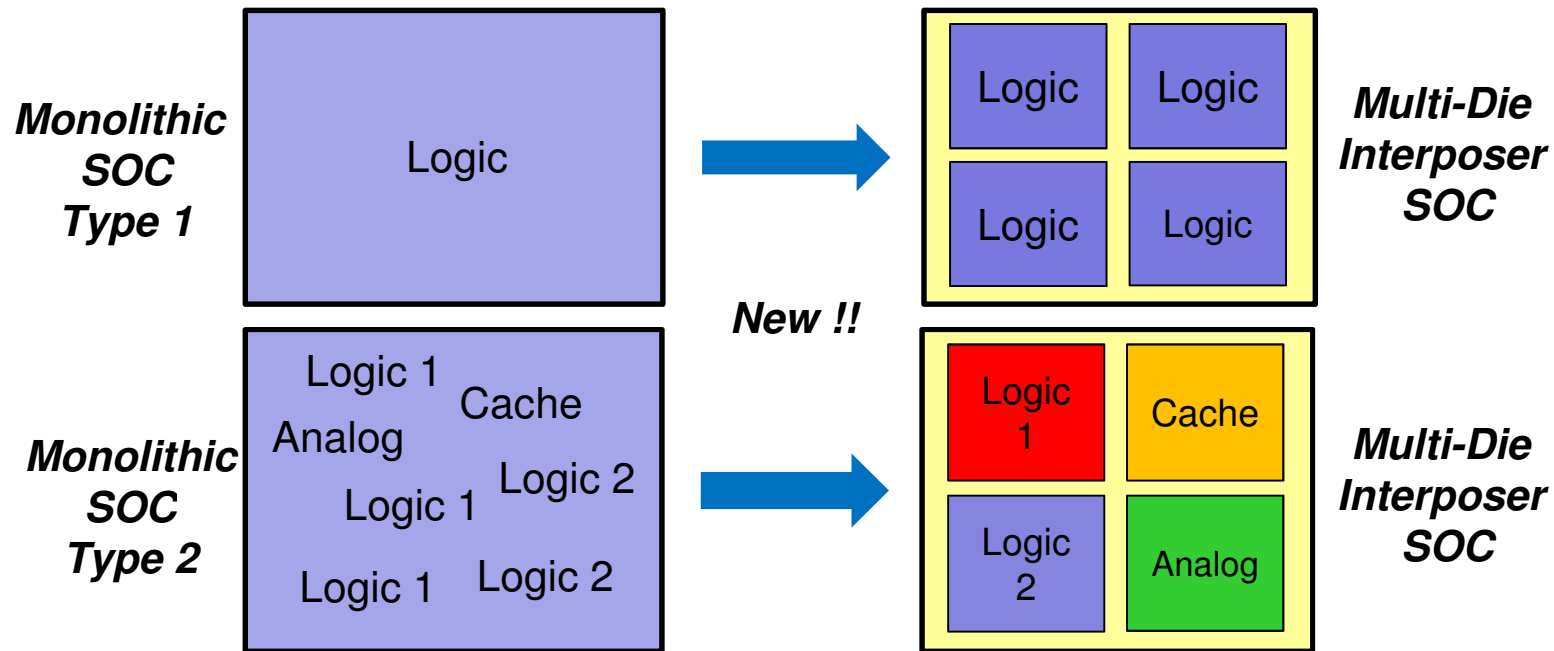




TSV Product Segments

- **3D Vertical Stacking**
 - Memory and Application Processor Driven
 - Today CSP focused on 28nm CMOS... scaling to 20/22nm
 - Application Processors almost exclusively moving to OSAT finished wafer process flows
- **2.5D Interposer – Side by Side Stacking**
 - Network, GPU and CPU driven
 - All large package body focused
 - All large silicon interposer focused (near retical size)
 - Both Foundry finished and OSAT finished wafer process flows being used

3DIC TSV Product Opportunities



- Focus process node development on specific application functionalities
 - ✓ Reduces complexity and mask layer count of process node
 - ✓ Reduces advanced process node 'Time to Market'
 - ✓ Improves wafer yield
 - ✓ Reduces wafer start cost
- Improves performance, power, and area of each application functionality

Primary Drivers for Interposers

Si Interp^T + DDR^T + Logic



Si Interp^T + Logic



Si Interp^T + Logic + SERDES



| Memory Bus Speed | Lower Power | Fab Yield | Cost | Stress Reduction in Top Die |
|----------------------|----------------------------------|------------------------------|------------------------------------|-----------------------------|
| Wide Parallel Busses | Wide Parallel Busses | Departition Fewer SoC Layers | System Level Reduction | ✓ |
| | Gate to Gate Routing between Die | Deconstruct into Smaller Die | Fab Yield Improve = Cost Reduction | ✓ |
| | | Departition (e-DRAM) | System Level Reduction | ✓ |



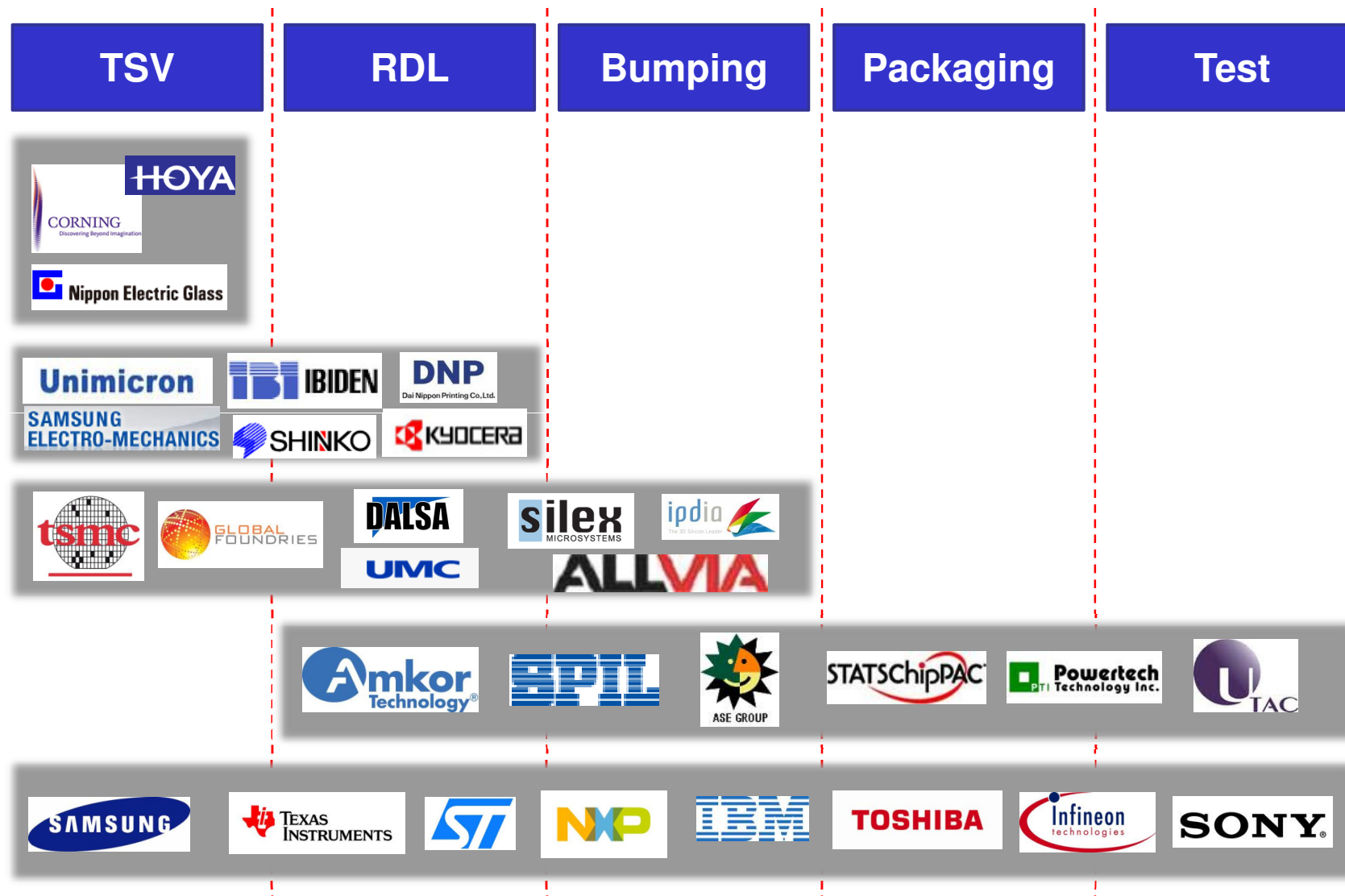
Interposer Supply Chain Logistics



Potential Interposer Technologies

- **Laminate (Organic)**
 - Delivered in large panel format (500x500mm typ.) with film based dielectrics
 - Several elite substrate manufacturers investigating today
- **Glass**
 - Can be delivered in panel (large) or wafer (8") format at target thickness
 - Several companies investing in applicable capability to support packaged semiconductor products
- **Silicon**
 - Can be delivered in 8" or 12"
 - Several companies supporting this product space & a few others investigating
 - Leveraging idle foundry space on legacy node technologies

Who is Doing What?



Source : Yole, 2010



Interposer Supply Chain Challenges

- **Glass**

- Panel format is strongest asset ; leveraging panel display market
 - Panel format presents challenges for CMP based activities (i.e. damascene processing)
 - More compatible with polymer dielectrics and $\geq 5\mu\text{m}$ line/space
 - Large panel plating process & Cu thickness variation
- Via creation still very expensive in glass

- **Laminate (organic)**

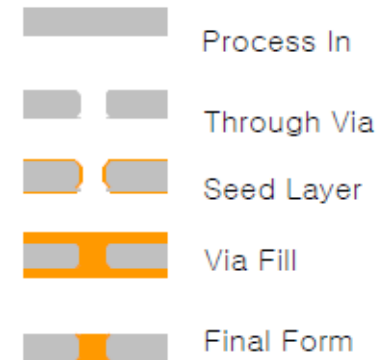
- Elite '5' substrate suppliers targeting this space
- Limited to $\geq 8\mu\text{m}$ line/space today and $40\mu\text{m}$ vias on $85\mu\text{m}$ pads
 - Development targeted at $5\mu\text{m}$ line/spacebut several years away
 - $5\mu\text{m}$ line/space requires stepper, and special resist technology
 - Via size/pad consumes too much space ; latency issues will limit adoption

Laminate vs Silicon Interposer

- Through via by laser drilling or mechanical punching



| Si Interposer | | S ³ Interposer |
|---|-------------------------|---------------------------------------|
| Wafer | Core Substrate Type | Panel |
| Silicon (3ppm/K) | Core Material | Organic (5ppm/K) |
| Dry Etch | Core Through Hole | Laser Via |
| PVD+Cu Plating (Semiconductor Process) | Through Hole Filling | E'less Cu+Cu Plating (PCB Process) |
| Wafer Thinning | Total Thickness Control | Core Thickness |
| 100% (8 inch) | Net Die | 135% (200 x 250 mm ²) |



60~300μm available

12 inch = primary path

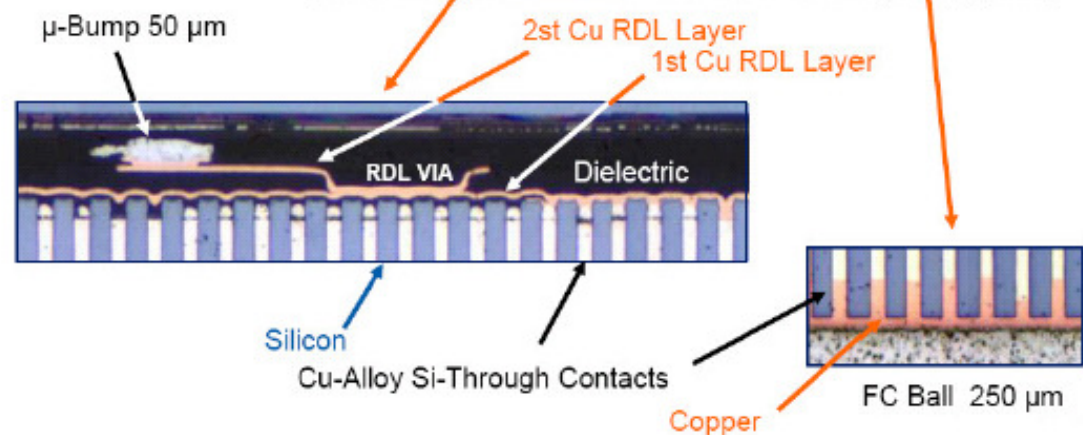
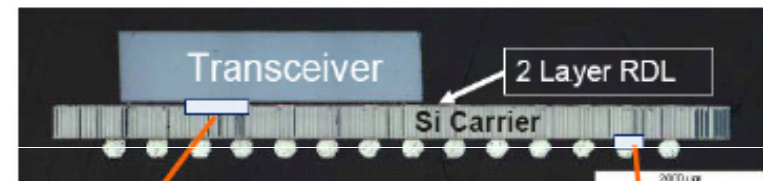
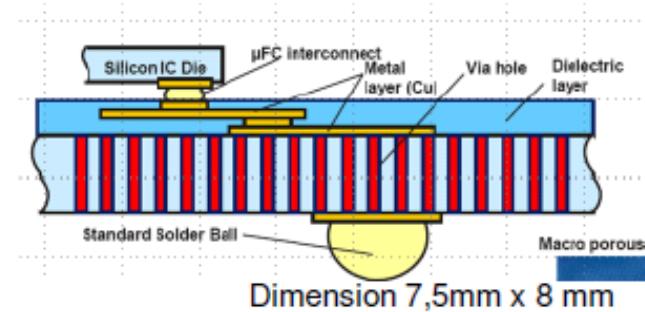
Source : Samsung Electro-Mechanics

Silicon Interposer as Substrate



- **RF Module – Mobile Transceiver**

- RDL at 20 μ m line/space
- ~8 μ m dia. & 300 μ m deep TSV
- Laminate could play ...but via / pad?
- Glass a better fit due to via size

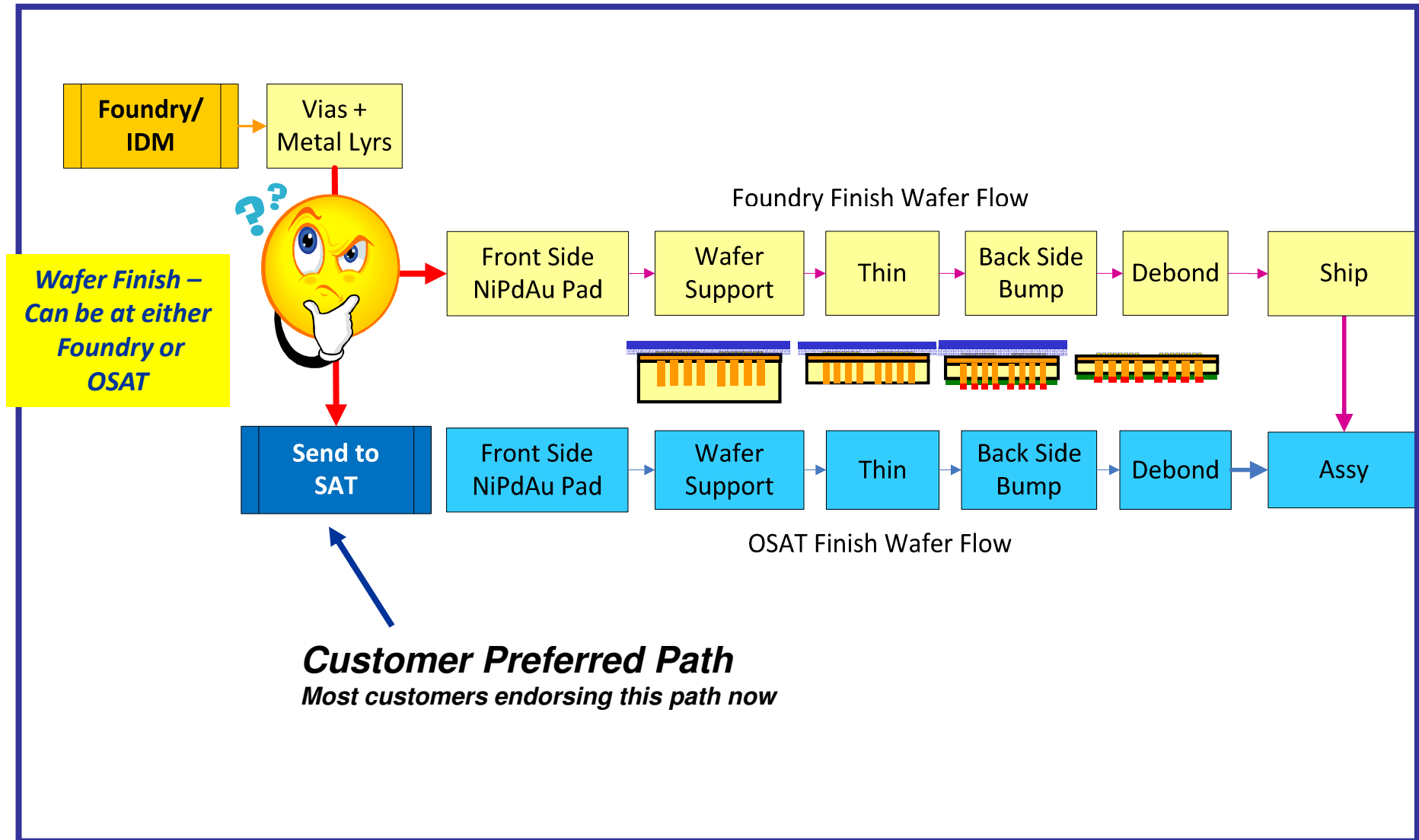


F. Binder, IFX M.J. Wolf

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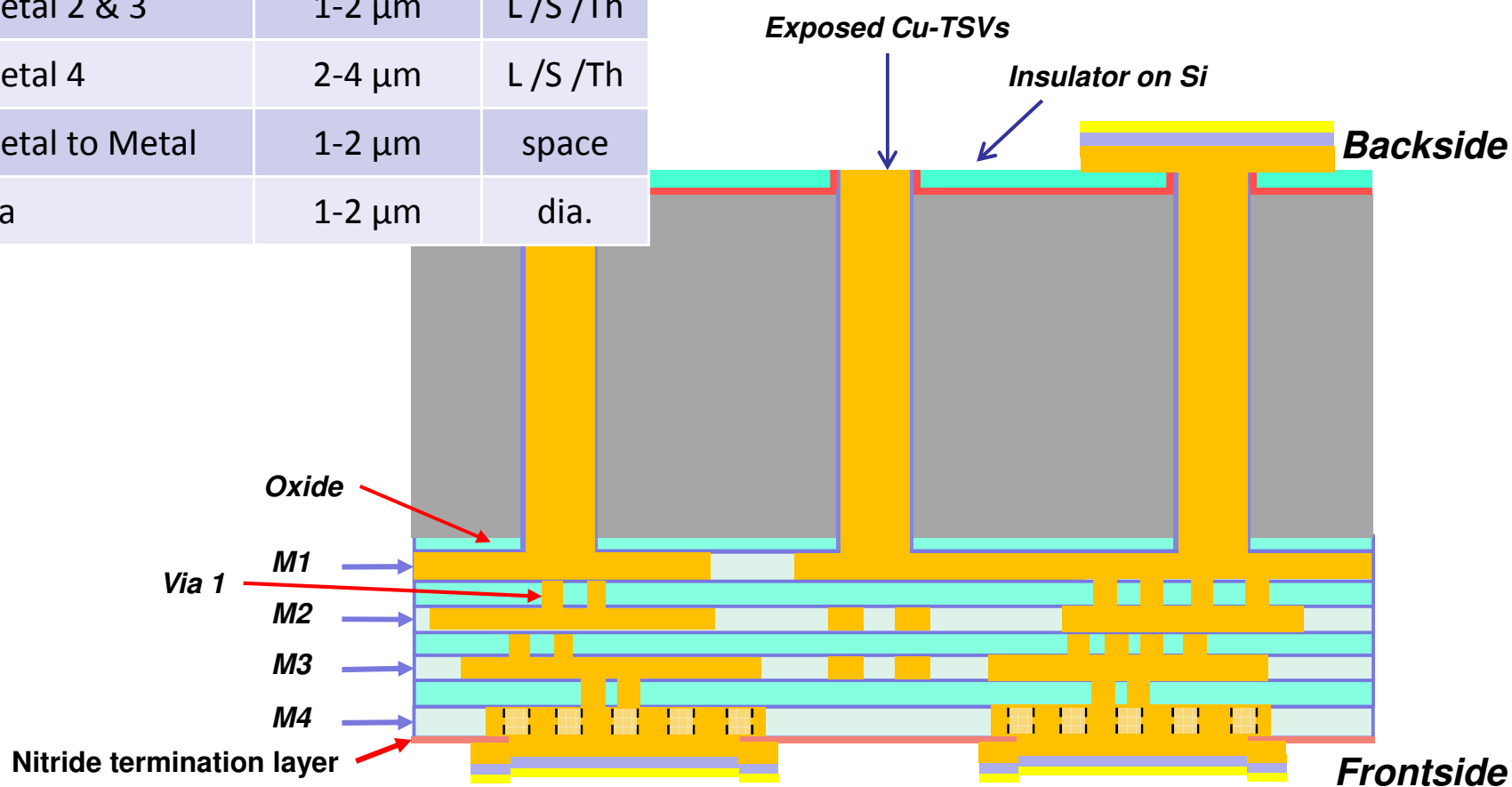


Interposer Supply Chain Issues – Silicon



Predominant Interposer Designs

| Feature | Spec | Note |
|-----------------|----------------------|------------|
| TSV dia./ depth | 10/100 μm | finished |
| Metal 1 | 1 μm | L / S / Th |
| Metal 2 & 3 | 1-2 μm | L / S / Th |
| Metal 4 | 2-4 μm | L / S / Th |
| Metal to Metal | 1-2 μm | space |
| Via | 1-2 μm | dia. |





Silicon Interposer Supply Chain

- **Sources**

- Several foundry sources interested in manufacturing silicon interposers
- A couple of sources already delivering fully functional wafers

- **Activity**

- Significant activity underway
- General target is 100µm as finished thickness with some backside RDL
- Some with passive components on top side of interposer
- Both heterogeneous and homogeneous die layouts

- **Challenges**

- Design rules are aggressive < 2µm line/space with up to 5µm vias
- Design rules fit low technology node BEOL silicon very well
- Copper damascene (dual) & 300mm wafer requirement don't necessarily match up with idle capacity



Interposer Supply Chain Summary

- **General**
 - Need to strengthen supply chain ; must entertain many alternative solutions
- **Laminate (Organic)**
 - Several companies reviewing cost add allowance & volumes to justify investment
 - Current limitations in via/pad design rules will limit market scope / application
- **Glass**
 - Panel size is best attribute ; LCD / flexible display in broad use
 - Via generation cost and plating distribution challenges will limit adoption
- **Silicon**
 - Foundries dominating supply chain, but only '3' real players today
 - Ultimately, cost needs to be in-line with market pricing to allow broad adoption



TSV Products Entering Market

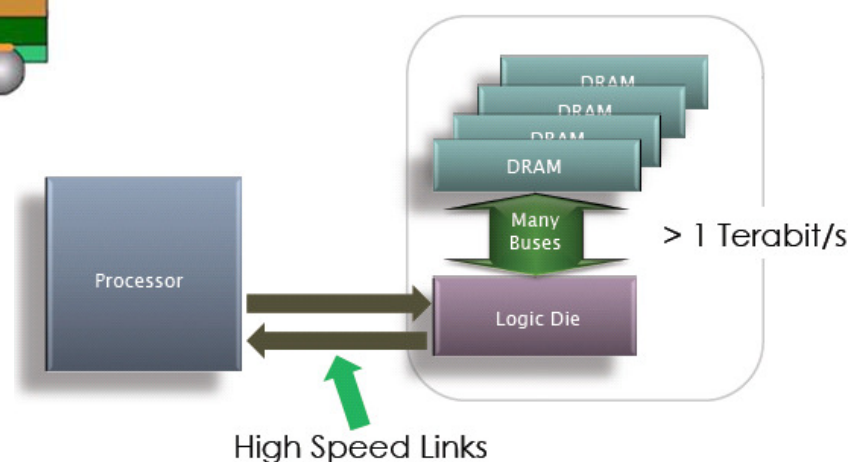
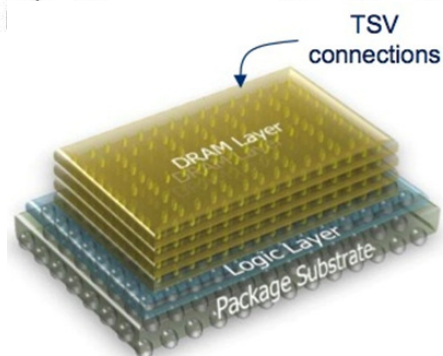
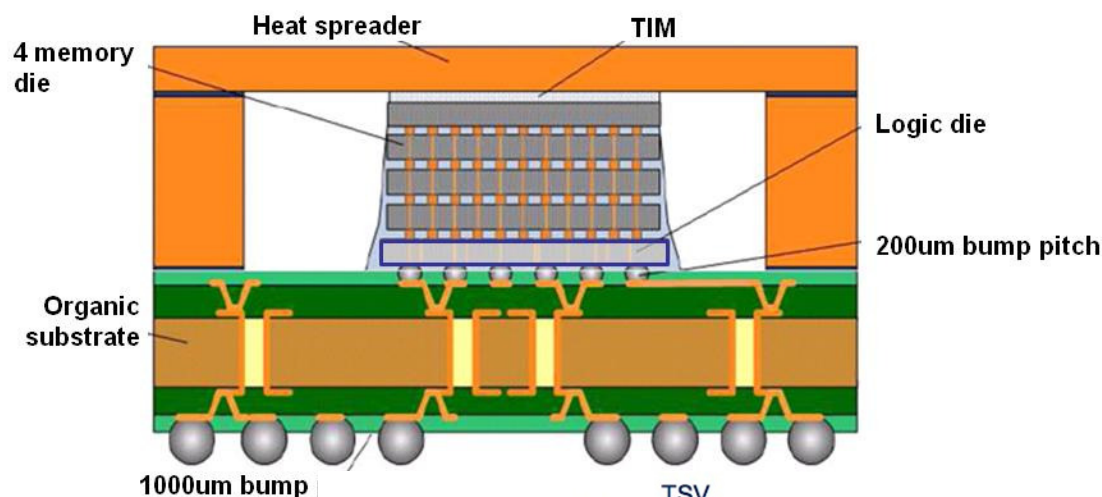
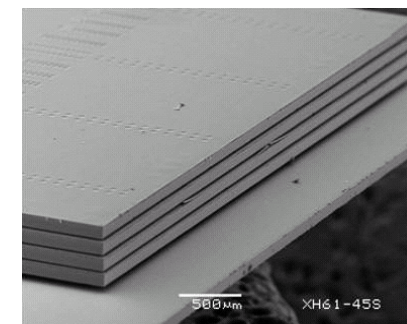
“Over Next Few Years”

3D CSP Based Vertical Stacks



- **Memory**

- Very high bandwidth at > 1 Tb/sec
- Used for high performance server & super computer (HPC)
- Eventually, Wide I/O DDR

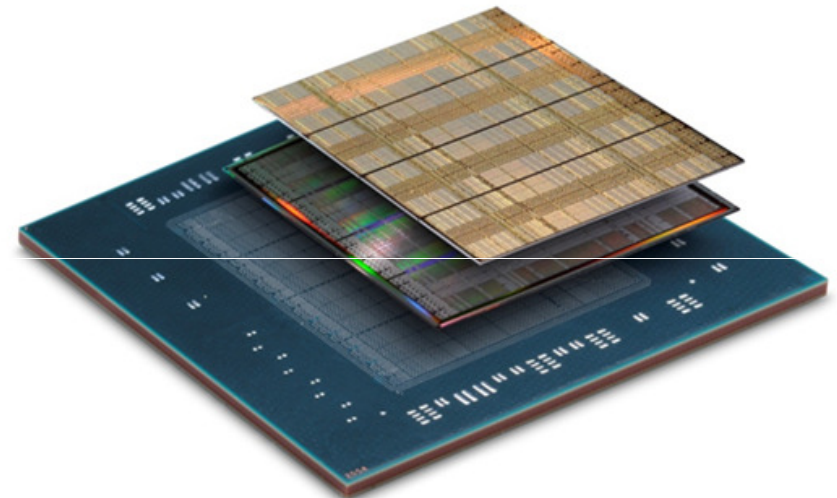


2.5D Silicon Interposer Based Product

- **FPGA Package Build Structure**

- ✓ Design increases logic capacity while reducing power
- ✓ 100X improvement in inter-die bandwidth / watt
- ✓ 50% power reduction from 40nm
- ✓ 5x reduction in latency
- ✓ 20x denser wire pitch

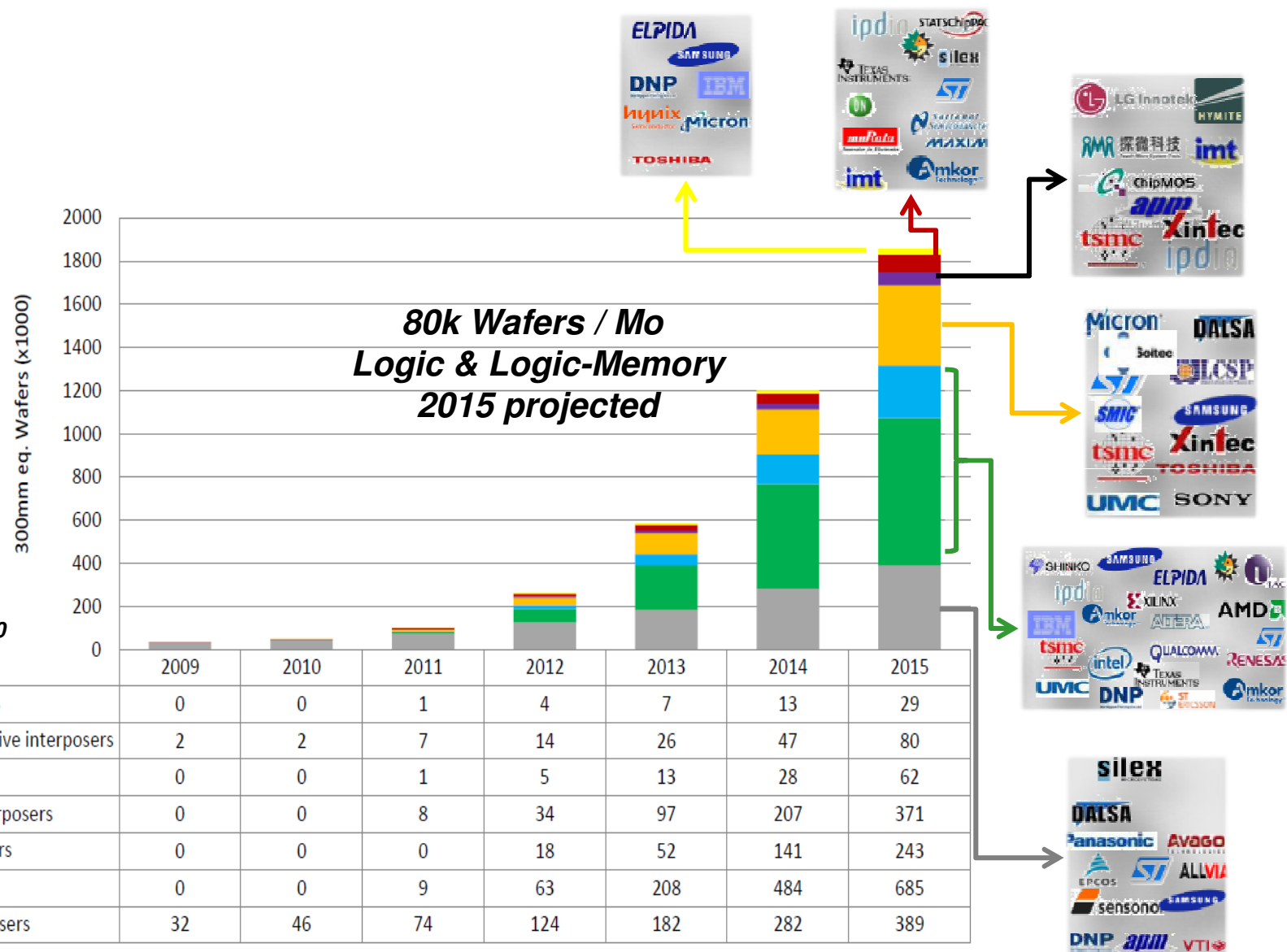
- FPGA ~ 8mm x 24mm
 - > 50,000 μ bumps per die
 - > 200,000 total μ bumps per package
- Interposer ~ 31mm x 25mm
 - ~20,000 C4 bumps per interposer
 - minimizes heat flux issues
- Substrate
 - 45mm body with ~ 2000 BGA balls



***Ramping
into production
Today !!***

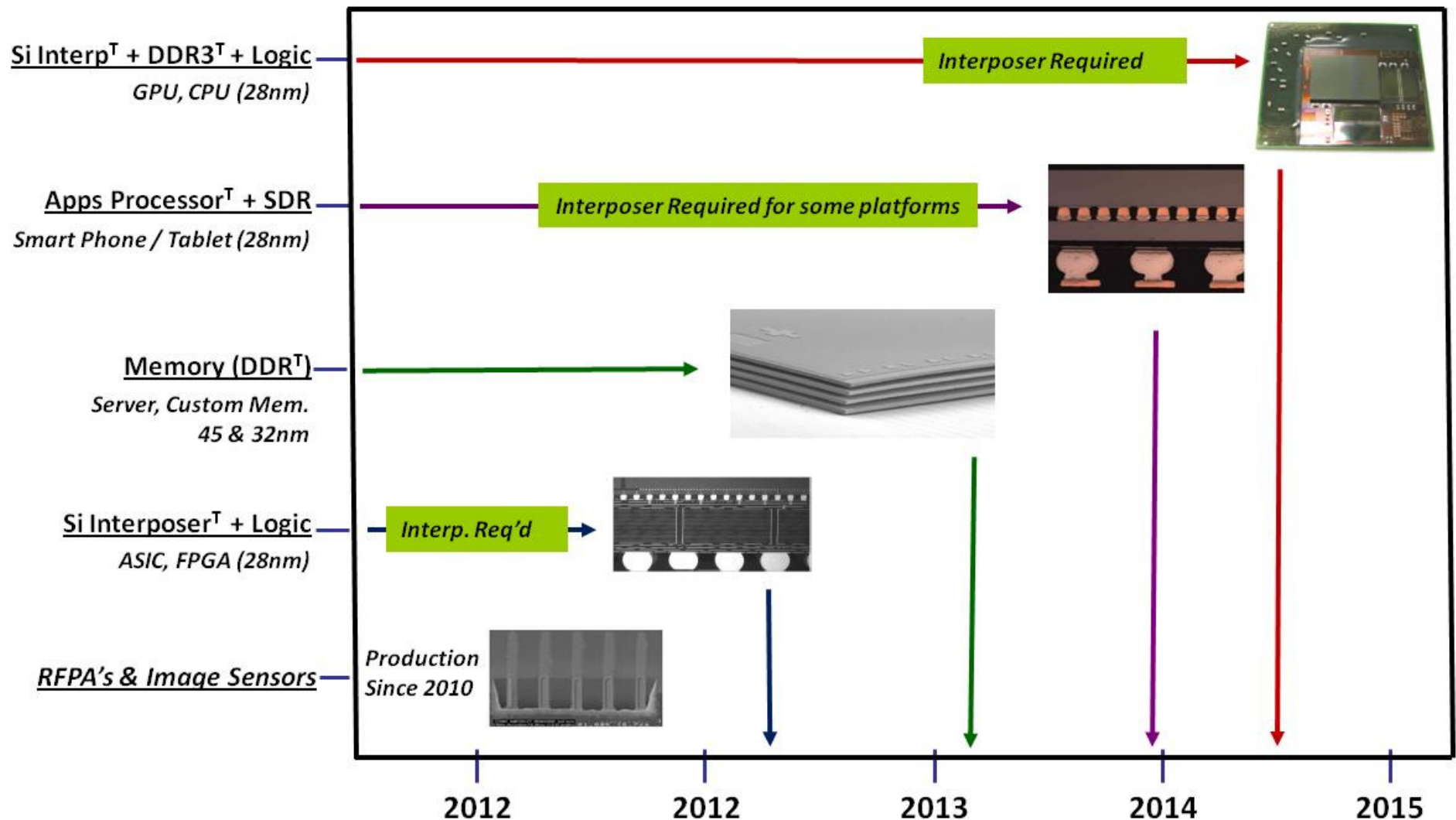
*Xilinx's Virtex-7® 2000T device showing from top to bottom
the packaging substrate, the silicon interposer & 4 FPGA die
(courtesy of Xilinx)*

2.5D Interposer Wafer Forecast by Application



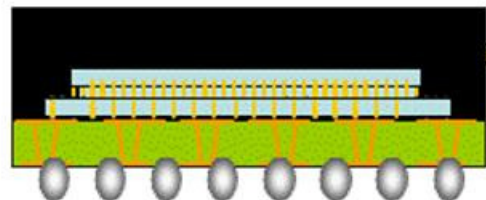
Expect compound annual growth > 80% over next 3 years through 2015 (300mm eq.)

TSV General Production Intercepts

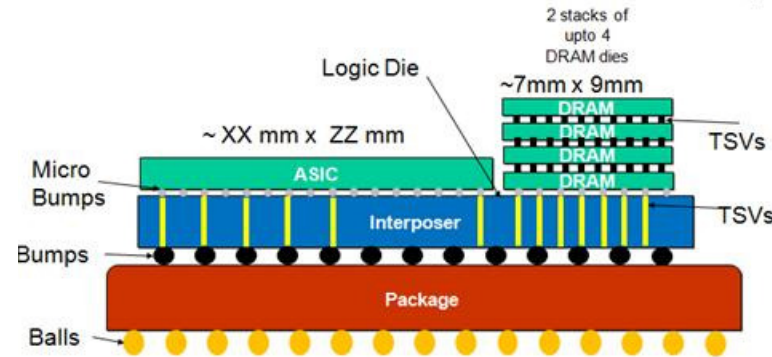


Die with TSV indicated by = T

Conclusion :TSV Product Future is 'Very Bright'



TSV Stacked CSP



TSV Stacked BGA

- Interest and activity accelerating
- 3D CSP Form Factor Improvement
- 2.5D Reduces Complexity
 - ✓ Reduces mask layer count of process node
 - ✓ Reduces advanced process node 'Time to Market'
 - ✓ Improves wafer yield
 - ✓ Reduces wafer start cost
- Both Improve Performance & Reduces Power Requirement

Thank You!

